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UNITED STATES PATENT AND TRADEMARK OFFICE
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**DECISION ON PETITION** 

TO WITHDRAW THE

HOLDING OF ABANDONMENT

## MALED

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DIRECTOR'S GFFICE
TECHNOLOGY CENT® 3600

In re Application of

Richard N. Savage et al. Application No. 09/767,659

Filed: January 22, 2001

For: SEMICONDUCTOR

SEMICONDUCTOR WAFER PROCESSING

SYSTEM WITH VERTICALLY-STACKED PROCESS

CHAMBERS AND SINGLE-AXIS DUAL-WAFER TRANSFER SYSTEM

This is in reply to the renewed petition to withdraw the holding of abandonment under 37 CFR 1.181, filed in the United States Patent and Trademark Office, on June 14, 2004.

The petition is <b>GRANTED</b> in view of the following evidence of timely filling:
Postcard receipt being dated
USPTO return facsimile receipt dated which identifies the application by serial number <u>and</u> the type of Response that was filed on that date.
○ Certificate of Mailing/Transmission signed on <u>April 29, 2003</u> and supported by a statement under 37 C.F.R. 1.8(b)(3).
Hand Delivery Receipt of the specific documents submitted dated
Certificate of Transmission of CPA under 37 C.F.R. 1.6 filed on
Express Mail Receipt under 37 C.F.R. 1.10 dated
This application is being forwarded to the Supervisory Legal Instruments Examiner for entry of the response filed with the petition, then to the examiner for prompt action on

SNM/vdb: 8/26/04

the response.

STEVEN N.º MEYERS
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